



OUTSTANDING SPECTRAL MEASUREMENTS OF OPTICAL COATINGS

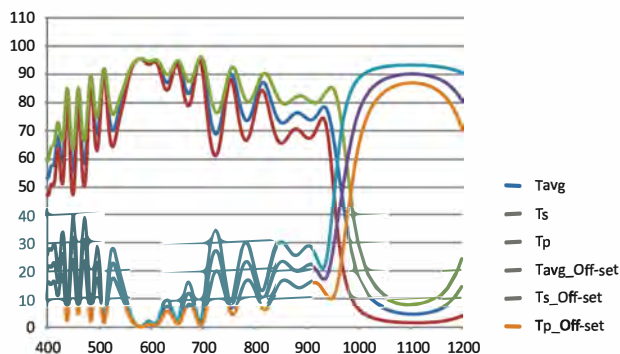
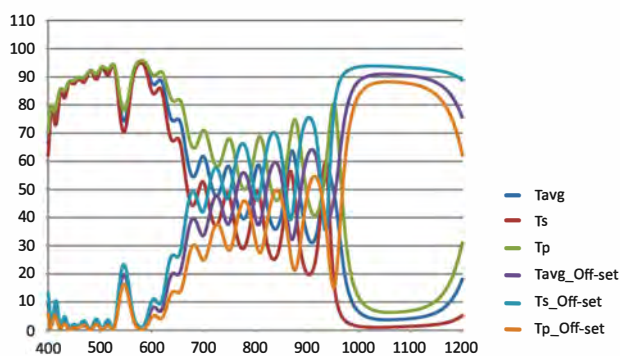
PHOTON RT

UV-VIS-MWIR SPECTRAL MEASUREMENTS OF PLANO OPTICS AND PRISMS

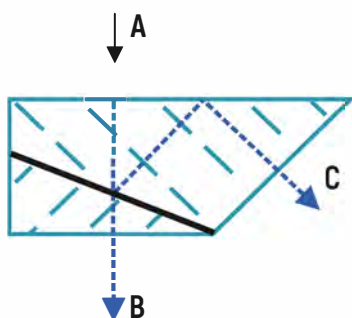


UNIQUE RESULTS*

↓ MEASUREMENT OF COMPLEX PRISMS WITH BEAM OFFSET



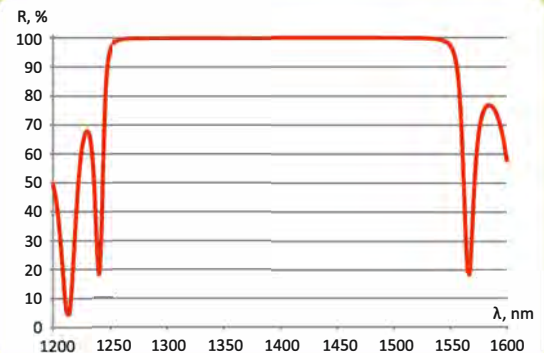
CEMENTED PRISM WITH BEAM OFF-SET



Measurement of beams B and C in one run without moving the sample

*The example results shown are ONLY obtainable by using the PHOTON RT

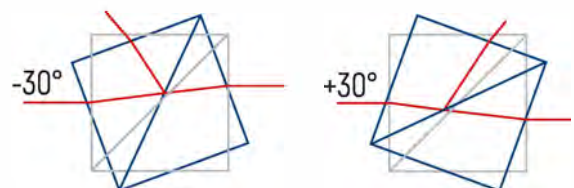
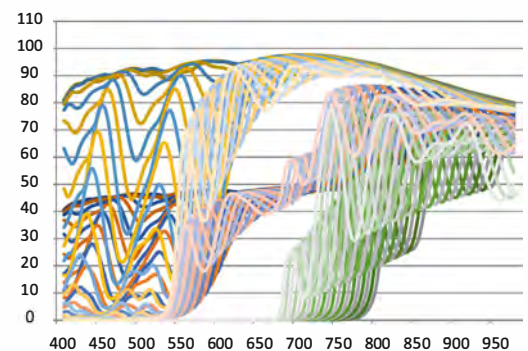
↓ 1392 nm BROADBAND NEAR IR LASER MIRROR



Max measured absolute specular reflectance:

99,9953%

↓ BEAM SPLITTER MEASUREMENTS AT VARIABLE AOI

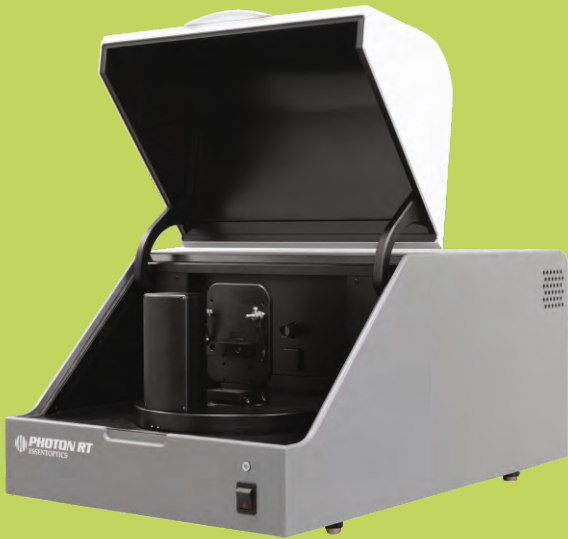


Designed specifically for optics used in AR and VR devices

PHOTON RT

THE ONLY INSTRUMENT DESIGNED SPECIFICALLY TO TEST OPTICAL COATINGS

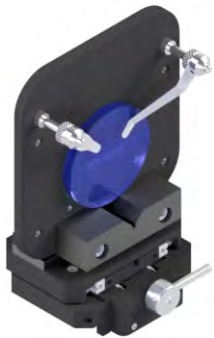
UNIQUE DESIGN



- ➔ Unique optical design – measurement from 185 nm up to 5200 nm in one instrument
- ➔ Multi-axis movement of the measurement channel – testing of sophisticated cemented prisms at any angles of incidence with variable off-set or arbitrary direction of the outgoing beam
- ➔ Special low-noise detectors are selected to qualify coatings with extreme specifications
- ➔ Optional sample stages designed for fast, complex or batch measurements
- ➔ Improved monochromator generates a highly collimated beam, produces low stray light and gives a high signal-to-noise ratio

AUTO-DETECT MOTORIZED STAGES

Z STAGE



Offers baseline calibration and subsequent test without user intervention

XY-MZF STAGE. MOTORIZED



Designed for testing a sample at multiple surface points

MULTIPLE SAMPLE STAGE



Designed for fully automatic testing of multiple samples including baseline calibration

SPECIFICATIONS

		PHOTON RT Spectrophotometer. Product Configuration	
MODEL	0217	0226	0252
OPTICAL CONFIGURATION			
Photometric functions	%T, %R		
Effective wavelength range, nm	185 - 1700	185 - 2600	185 - 5200
Built-in polarizer, nm	220 - 1700	220 - 2600	220 - 5200
Optical scheme of monochromator	Czerny-Turner		
Optics	Mirror, MgF ₂		
Reference channel	Yes		
Wavelength sampling pitch, nm	0,1 - 100		
Spot size on the measured sample, mm	6 x 2 → 2 x 2		
Turning pitch angle of sample stage	0,01 deg		
Turning pitch angle of photodetectors	0,01 deg		
Beam displacement compensation	- 60,0 mm ... 0 ... + 60,0 mm (actual value depends on detector position)		
Variable angle measurements	1. 0 - 75 deg for transmittance (up to 85 deg with 7085 sample stage) 2. 8 - 75 deg for absolute reflectance (up to 85 deg with 7085 sample stage) 3. Detector rotation range: 300 deg ... 180 deg ... 16 deg 4. Sample stage rotation range: - 85 deg ... 0 deg ... + 85 deg		
Wavelength subranges, nm	Ultimate spectral resolution, nm (non-polarized light)	Wavelength accuracy, nm	Wavelength repeat accuracy, nm
185 - 990 nm	0,6	+/- 0,5	+/- 0,25
990 - 1700 / 2450 / 2600 nm	12	+/- 1,0	+/- 0,5
2450 - 5200 nm	N/A	N/A	+/- 2,0
Stray light level, % at 532 nm	< 0,1		
Angle of beam divergence	+/- 1 deg		
Photometric accuracy	[VIS] NIST SRM 930e: +/- 0,003 Abs [1 Abs] NIST SRM 1930: +/- 0,003 Abs [0,33 Abs]; +/- 0,006 Abs [2 Abs] [MWIR] NRC NG11 SRM: +/- 0,0013 Abs [0,13 Abs]; +/- 0,0053 Abs [0,49 Abs]; +/- 0,0011 Abs [0,82 Abs]; +/- 0,005 Abs [1,0 Abs] Determined using 0,1 second accumulation, maximum deviation for 10 subsequent measurements		
Photometric repeat accuracy	[VIS] NIST SRM 930e: +/- 0,0004 Abs [1 Abs] NIST SRM 1930: +/- 0,0001 Abs [0,33 Abs]; +/- 0,005 Abs [2 Abs] [MWIR] NRC NG11 SRM: +/- 0,0003 Abs [0,13 Abs]; +/- 0,0008 Abs [0,49 Abs]; +/- 0,0022 Abs [0,82 Abs]; +/- 0,0034 Abs [1,0 Abs] Determined using 0,1 second accumulation, maximum deviation for 10 subsequent measurements		
Stability of baseline, %/hour [VIS range]	< 0,1 [one hour warm-up time]		
Unattended polarization measurements with built-in polarizers	S, P, [S + P] / 2		
Zero order / Green beam	Built-in, automatic		
Light sources, preinstalled	1. Deuterium lamp: 1 ea 2. Halogen lamp: 1 ea 3. IR source: 1 ea (model 0252) 4. HgAr wavelength calibration lamp: 1 ea		
Light sources, spare	Halogen lamp: 2 ea (included with shipment). Other spare light sources can be ordered additionally		
SAMPLE COMPARTMENT			
Dovetail baseplate for sample stages	Designed for mounting of motorized and non-motorized sample stages. Integrated controller ensures instant detection of the motorized stage		
Planar sample stage	For measurement of transmission and reflection of planar samples with size bigger than 12,0 x 10,0 mm		
Independent positioning	Independent computer controlled positioning of sample stage and photodetectors unit		
Synchronized positioning	Synchronized computer controlled positioning of sample stage and photodetectors unit depending on the selected photometric function		
Size of samples	Min. 12,0 x 10,0 mm - for measurement at 0 - 10 deg incidence angles Min. 12,0 x 25,0 mm - for measurement at 10 - 75 deg incidence angles Max. sample size: • up to 152,4 mm [6"] with closed lid for standard sample stage • up to 140,0 mm [5 1/2"] with closed lid for Z sample stage		
Sample stage for PBS cubes	50,0 x 50,0 x 50,0 mm sample stage with two additional cube holders 1" x 1" x 1" and 1/2" x 1/2" x 1/2"		
Optional motorized and non-motorized sample stage	1. MP Stage. Multiple sample measurement 2. XY Stage. XY sample mapping 3. XY-MZF Stage. Measurement of multi-zone filters and linear variable filters 4. Z Stage. Sequential baseline calibration and sample measurement without opening the lid 5. QW Stage. Testing of wave plates 6. R Stage. 360 deg rotation of the sample around the beam axis 7. 7085 Stage. Measurement at extreme angles of incidence up to 85 deg		
INTERFACE, DIMENSIONS AND WEIGHT			
Interface	USB 2.0, Windows-based, English		
File saving options	res (txt), xls, pdf, csv		
Power consumption, Watt	110		
Power input	110-220 V (+/- 10%), 50-60 Hz		
Width x Depth x Height, mm (inches)	425 x 625 x 285 [16 3/4" x 24 2/3" x 10 1/5"]		
Net weight, kg [lbs]	50 [110]		



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超高真空・極低温走査型プローブ顕微鏡
高速分光測定装置、クライオスタット



Nd:YAGレーザー、Ti:Sレーザー
OPOLレーザー

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